

A Tunnel FET Design for High-Current, 120 mV Operation

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What does VLSI need ?

Low voltage

low switching energy $CV_{DD}^2/2$.

Large on-current

small delay CV_{DD}/I .

Low leakage current

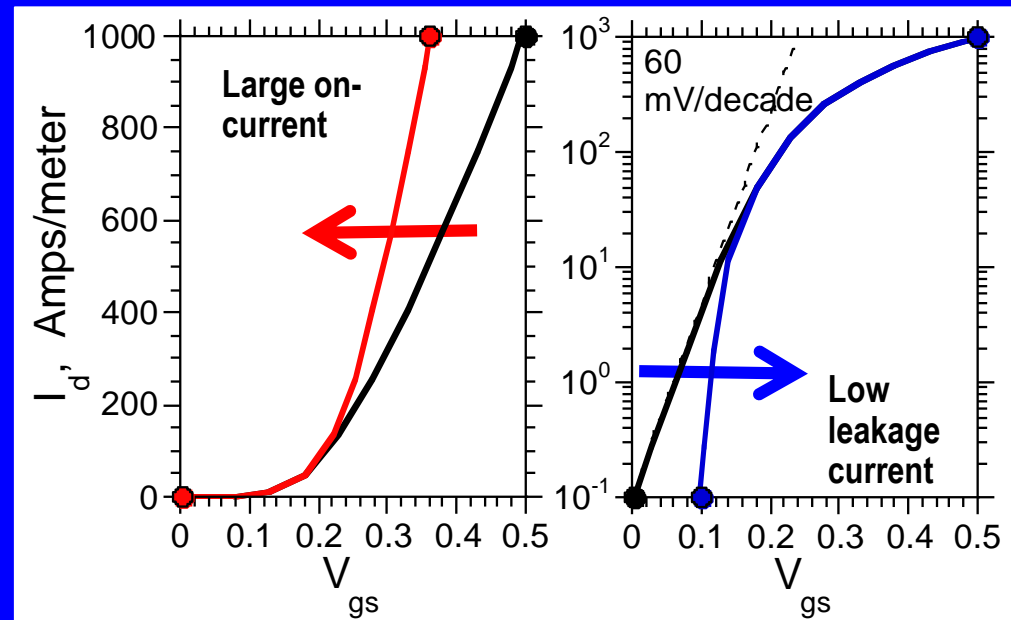
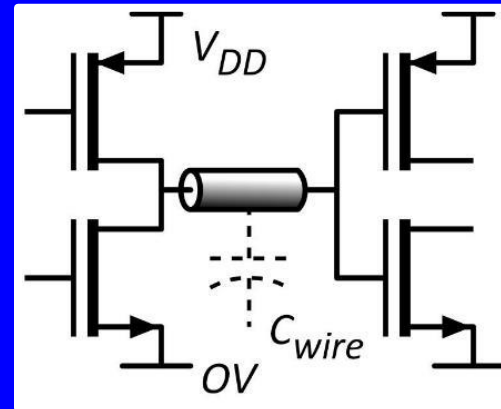
thermal: $I_{off} \propto \exp(-qV_{DD}/kT)$
want low V_{DD} yet low I_{off} .

Want:

low supply voltage

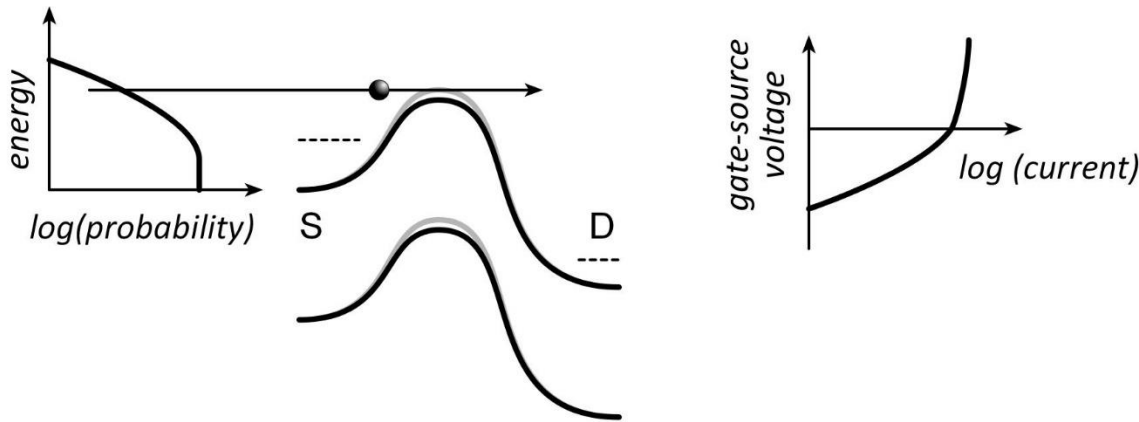
→ Steeper than 60mV/dec below threshold

→ Large dI/dV above threshold

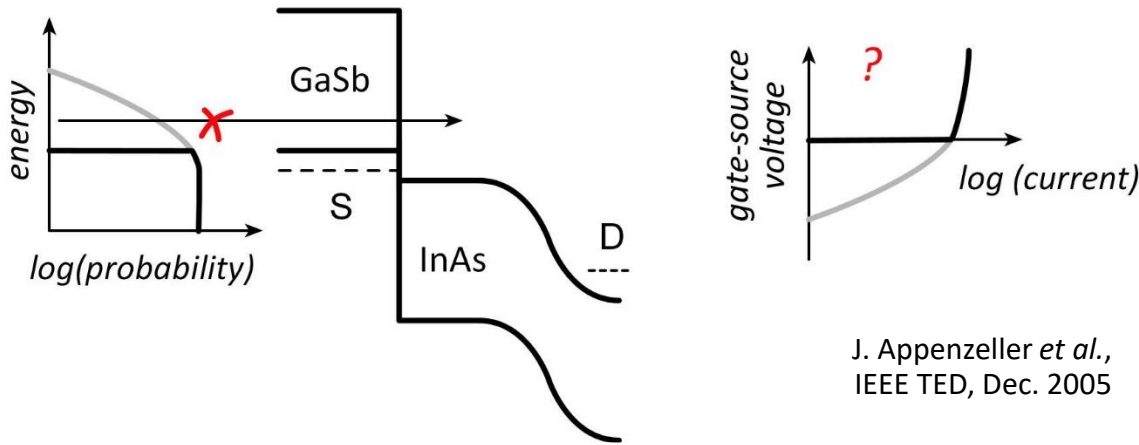


Tunnel FETs: truncating the thermal distribution

MOSFET



T-FET



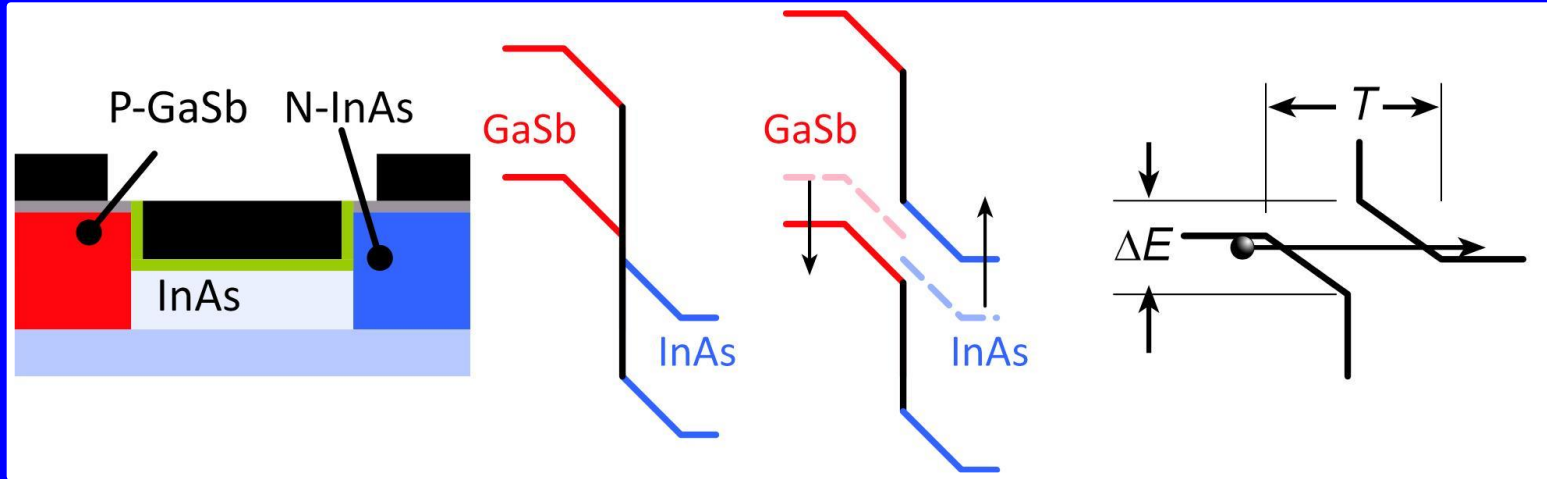
J. Appenzeller et al.,
IEEE TED, Dec. 2005

Source bandgap truncates thermal distribution → steep S.S. ✓

Must cross bandgap: tunneling → low I_{ON} ✗

Fix (??): GaSb/InAs broken-gap heterojunction

Tunnel FETs: are prospects good ?



Useful devices must be small: short gate \rightarrow thin channel

Quantization shifts band edges \rightarrow tunnel barrier

Confinement also increases effective masses

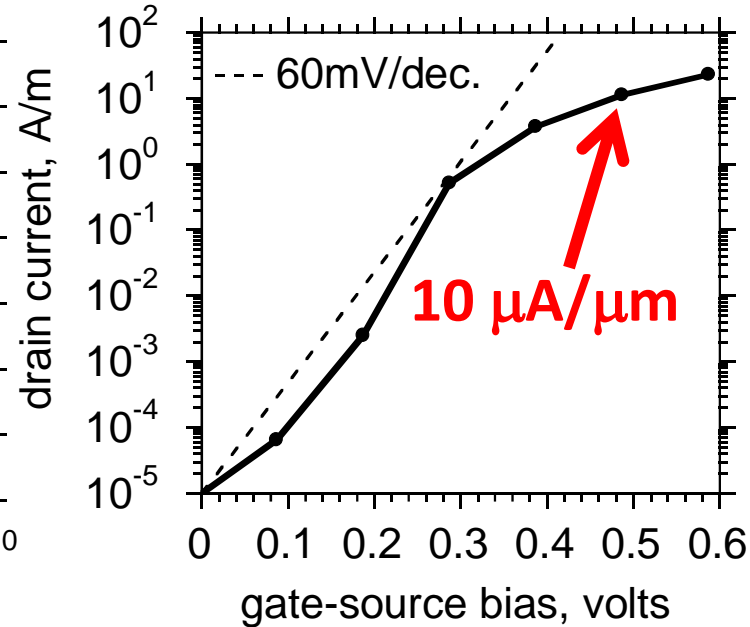
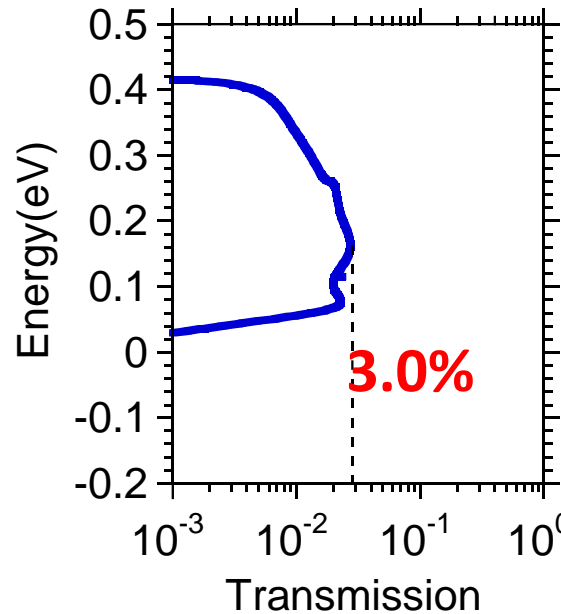
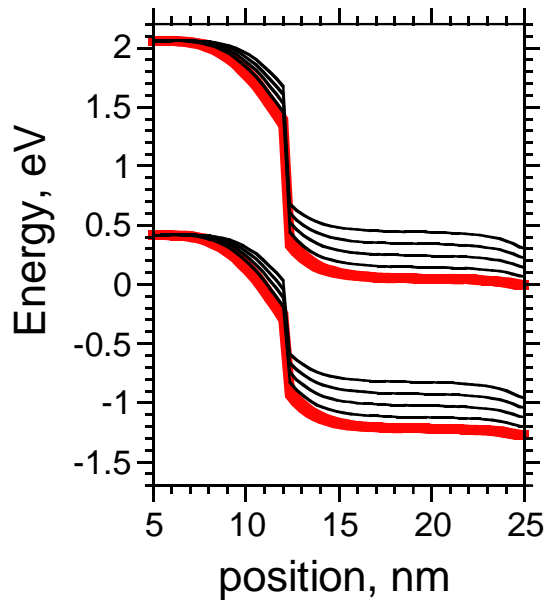
Transmission $\cong \exp(-2\alpha T_{barrier})$, where $\alpha \cong \frac{(2m^*E_{barrier})^{1/2}}{\hbar}$
~10% for a 2nm barrier, 1% for a 4nm barrier

What actual on-current might we expect ?

T-FET on-currents are low, T-FET logic is slow

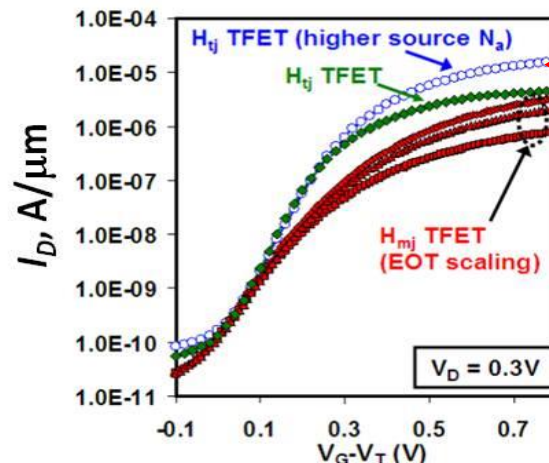
NEMO simulation:

GaSb/InAs tunnel finFET: 2nm thick body, 1nm thick dielectric @ $\epsilon_r=12$, 12nm L_g



Experimental:

InGaAs heterojunction HFET;
Dewey et al,
2011 IEDM,
2012 VLSI Symp.



~15 $\mu\text{A}/\mu\text{m}$ @ 0.7V

**Low current
→ slow logic**

**How to increase
on-current?**

Increasing the on-current

Trick #1: (110) confinement, $[1\bar{1}0]$ transport

P. Long *et al.*, EDL 3/2016

Reduces tunnel barrier height

Reduces hole mass

Trick #2 : channel heterojunction

P. Long *et al.*, EDL 3/2016

Reduces tunnel barrier thickness

Adds resonant state Avci & Young, (Intel) 2013 IEDM

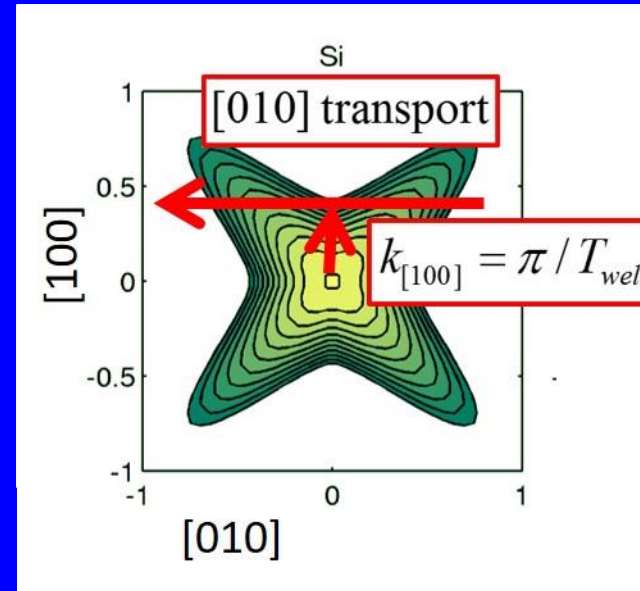
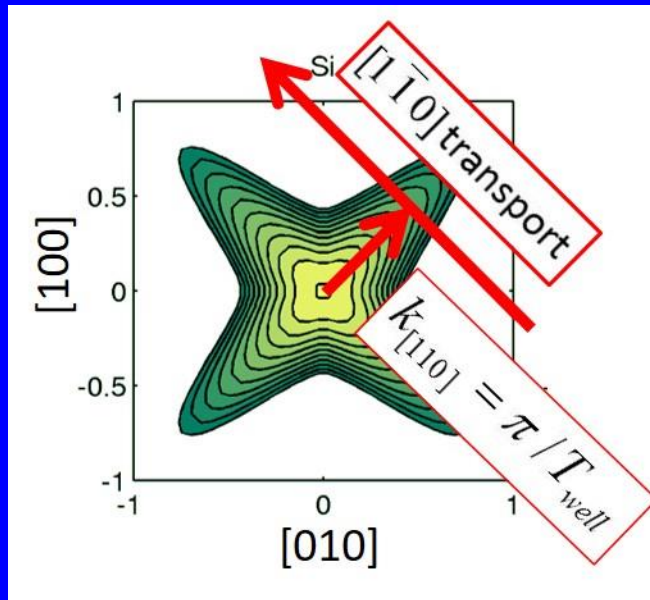
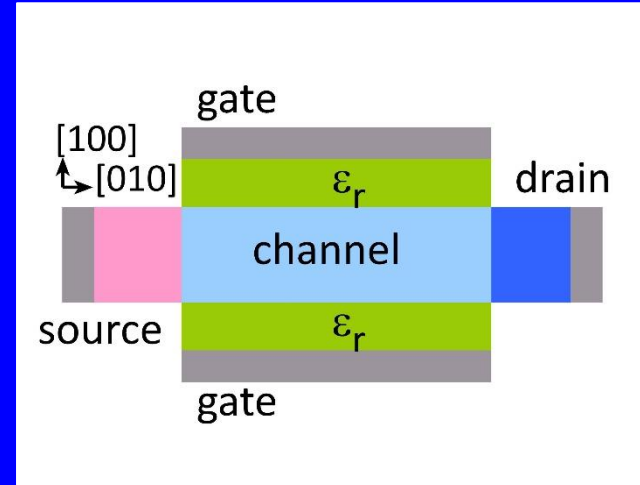
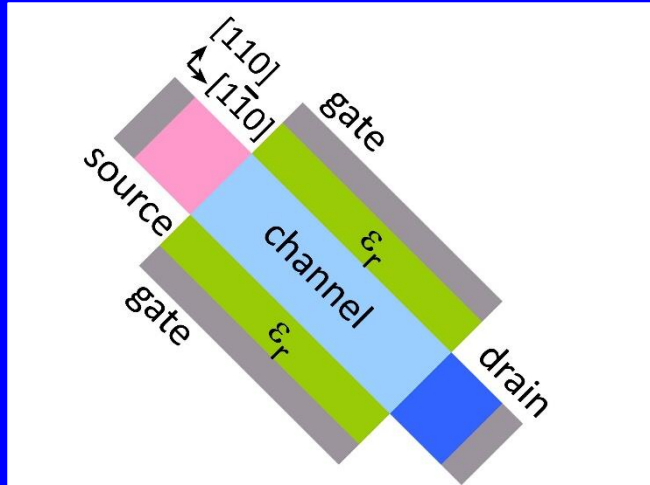
Trick #3 : source heterojunction

S. Brocard, *et al.*, EDL, 2/2014

Reduces tunnel barrier thickness

Adds resonant state

[110] gives more on-current than [100]

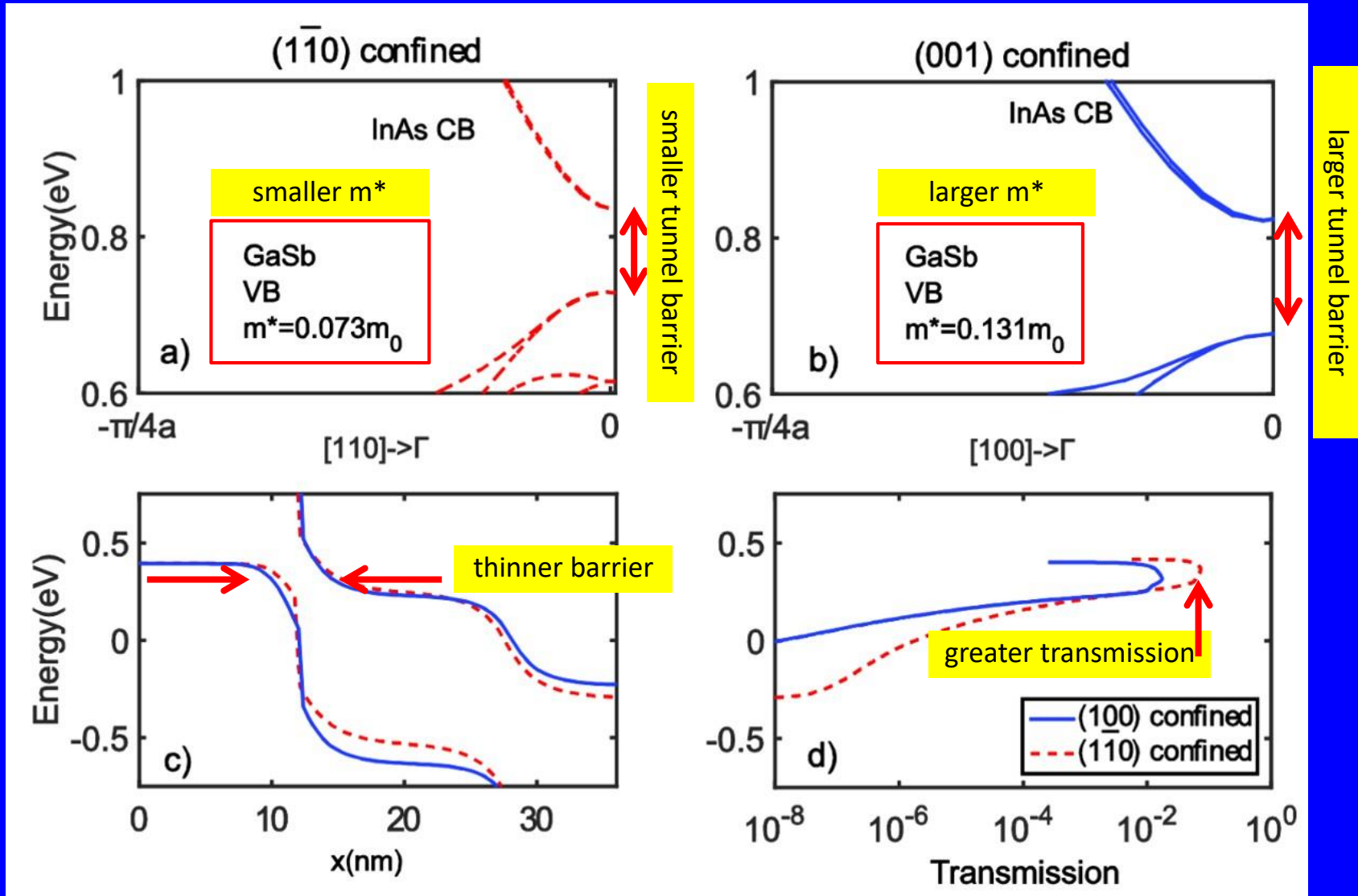


Valence Band

high confinement mass
low transport mass

low confinement mass
high transport mass

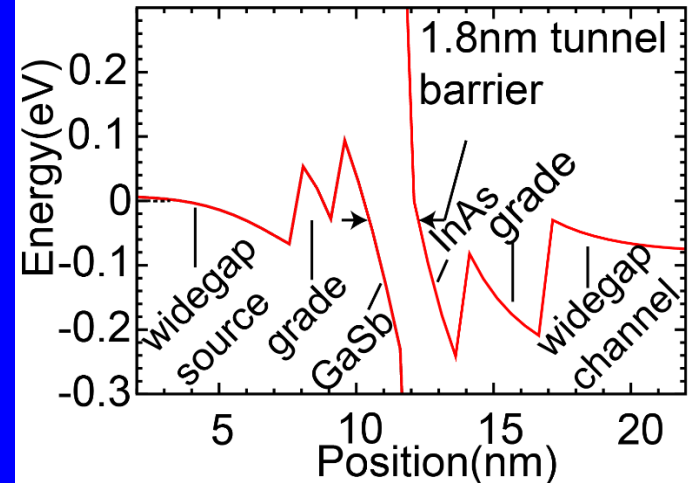
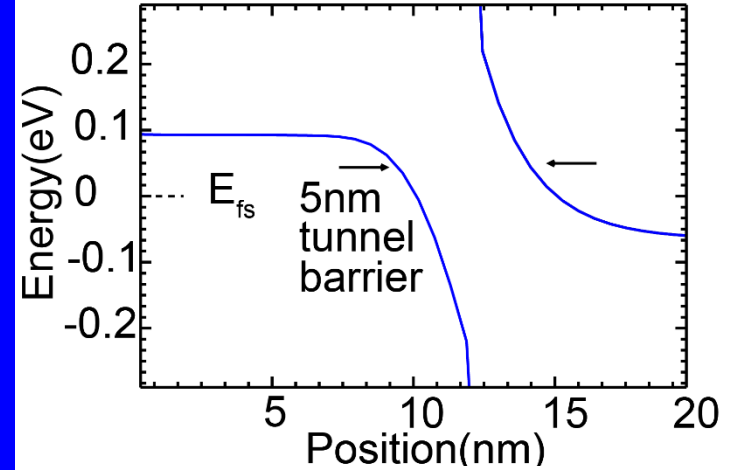
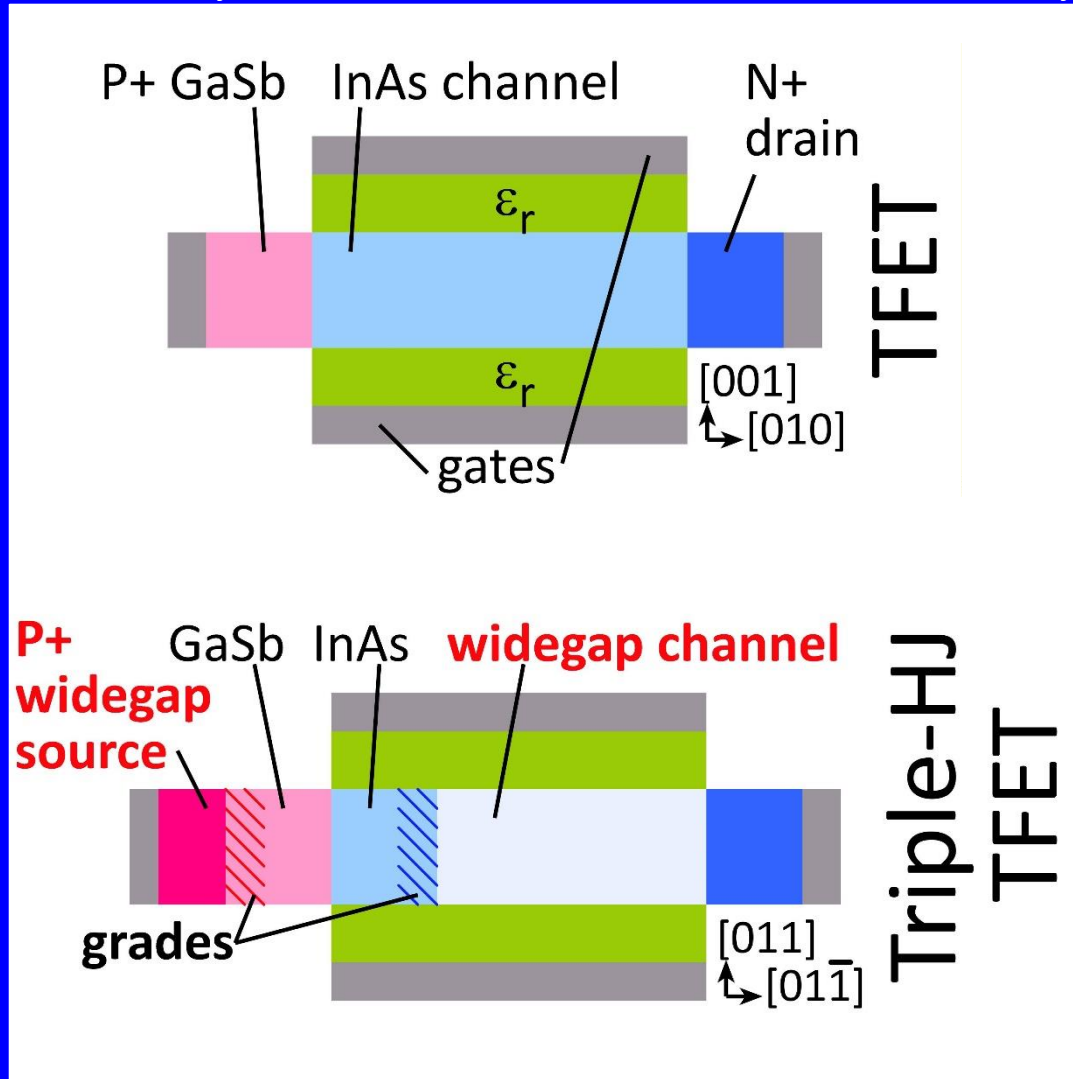
[110] gives more on-current than [100]



larger hole confinement mass \rightarrow smaller barrier \rightarrow more current
 smaller hole transport mass \rightarrow more current

Heterojunctions increase the junction field

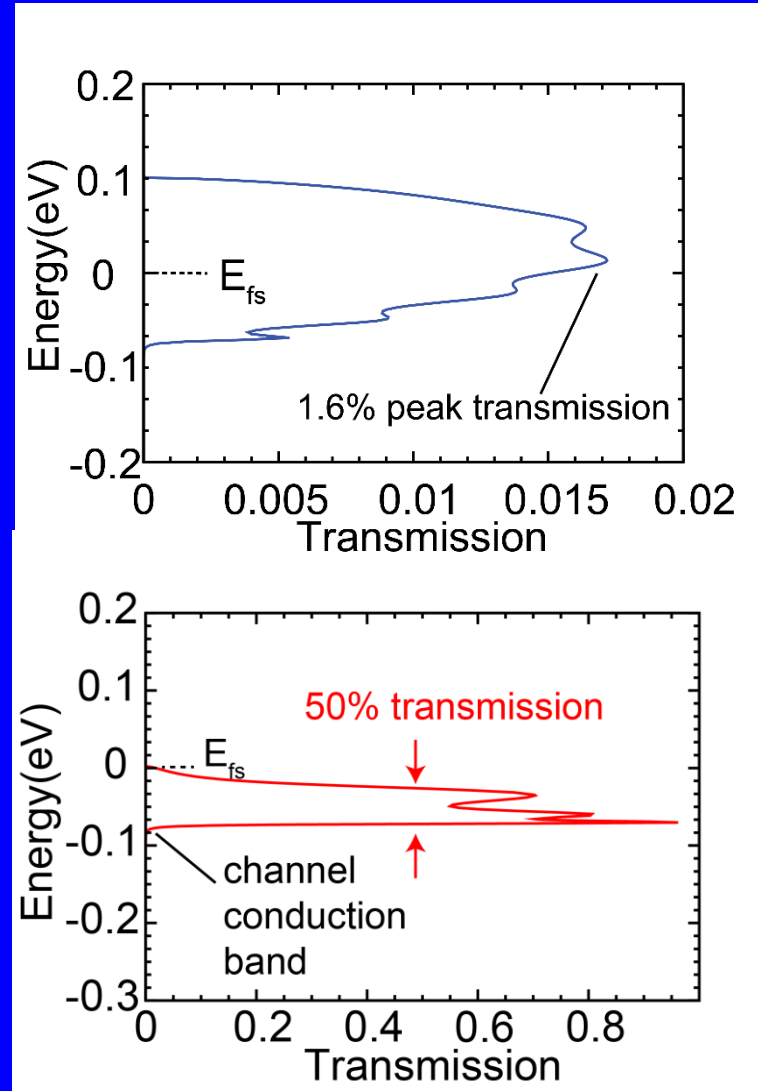
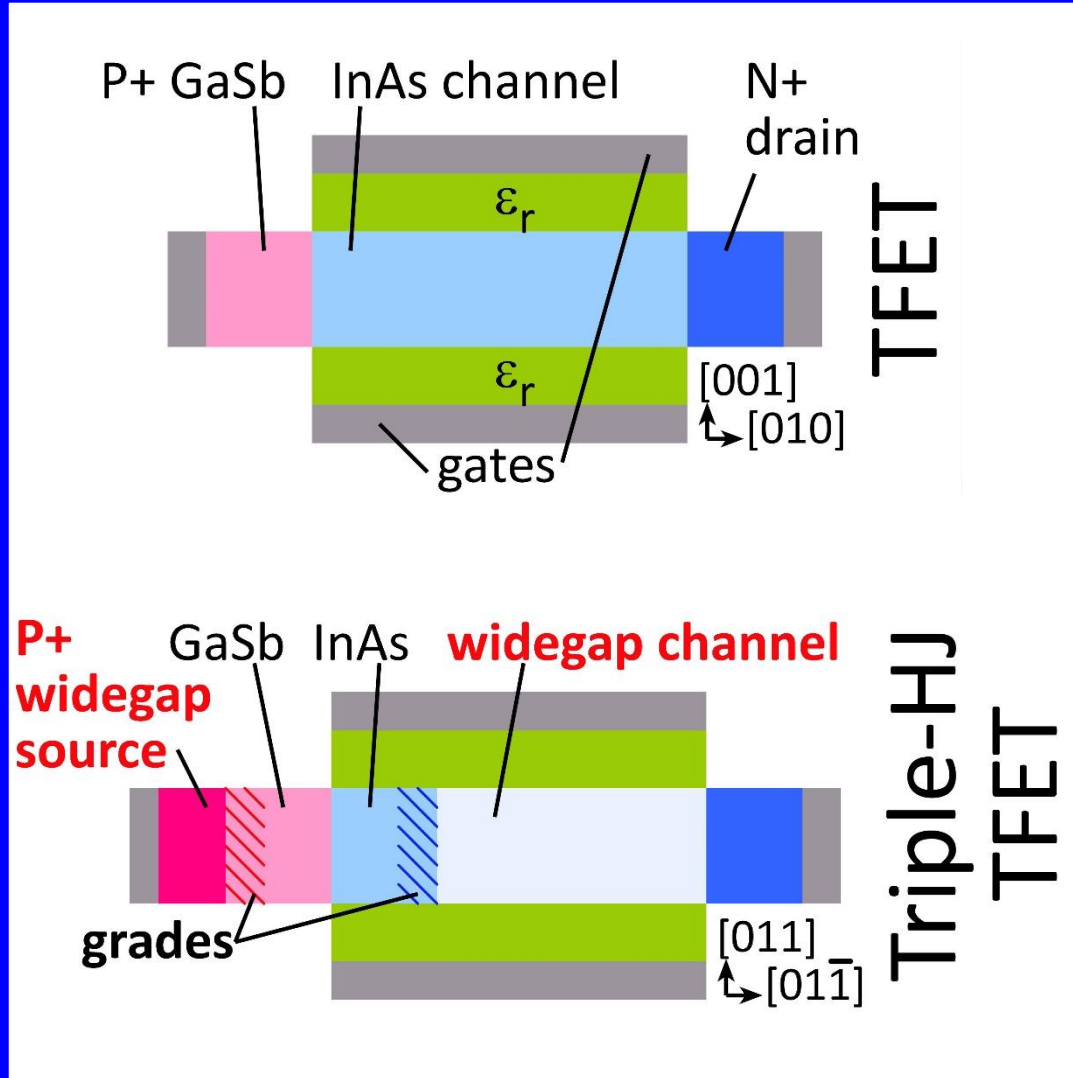
Source heterojunction: S. Brocard, *et al.*, EDL, 2/2014; Channel heterojunction: P. Long *et al.*, EDL 3/2016



Added heterojunctions \rightarrow greater built-in potential \rightarrow greater field \rightarrow thinner barrier

Heterojunctions increase the tunneling probability

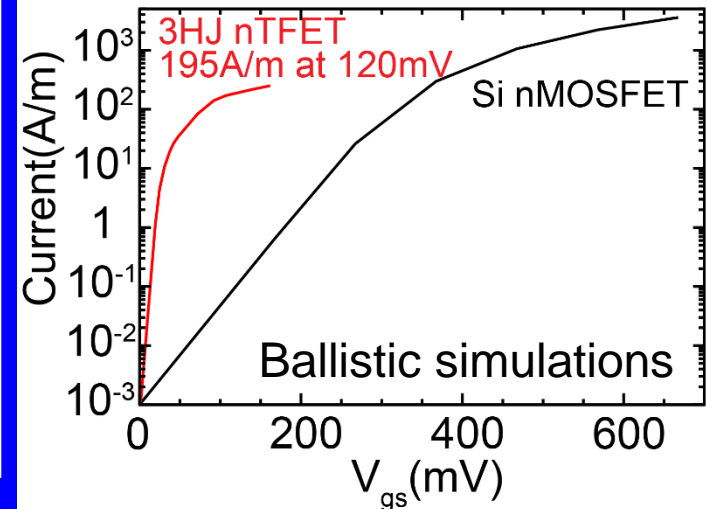
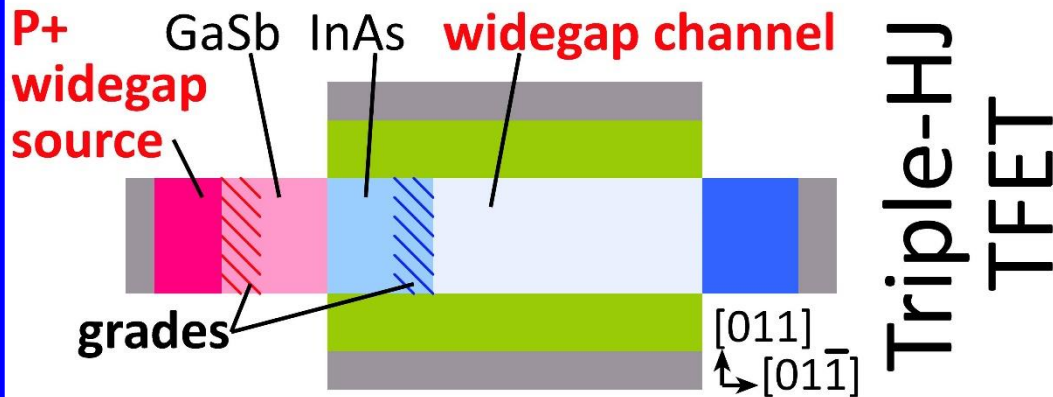
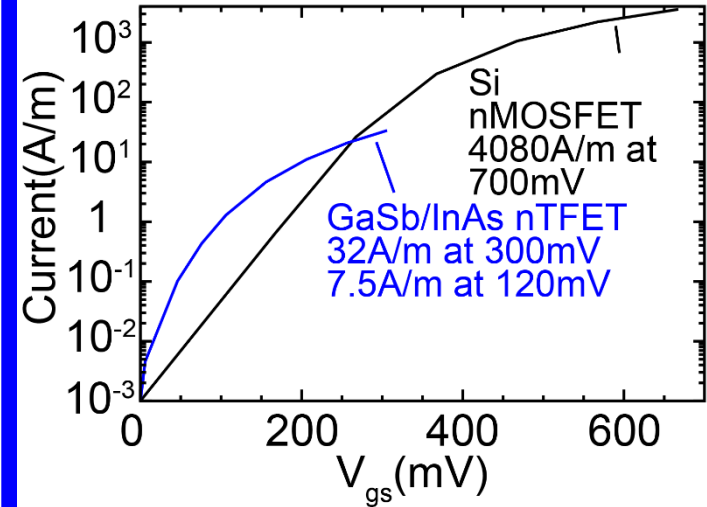
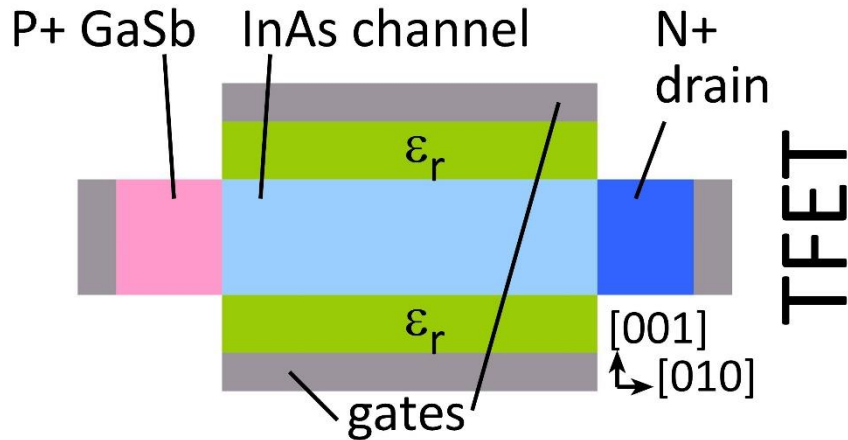
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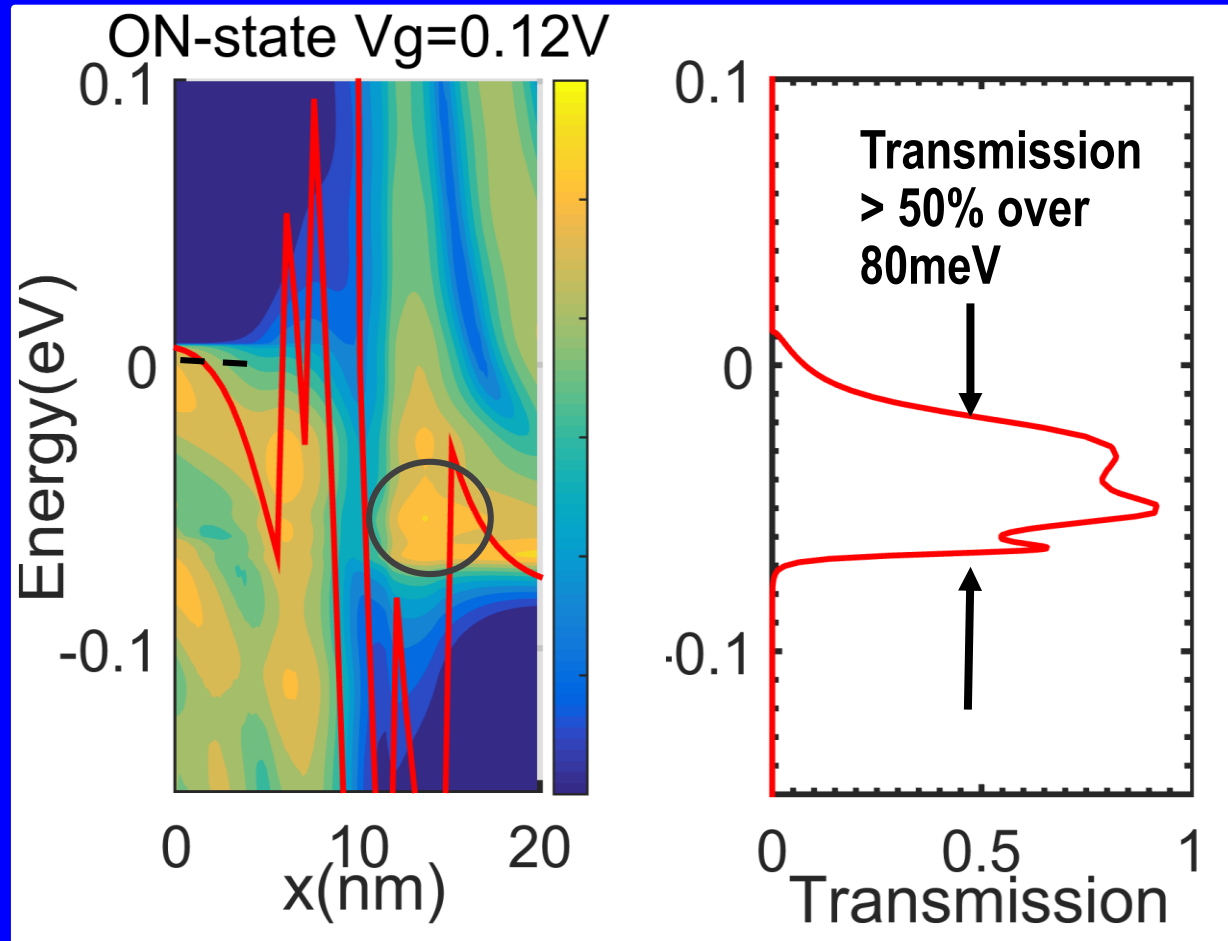
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Added heterojunctions → greater built-in potential → greater field → thinner barrier

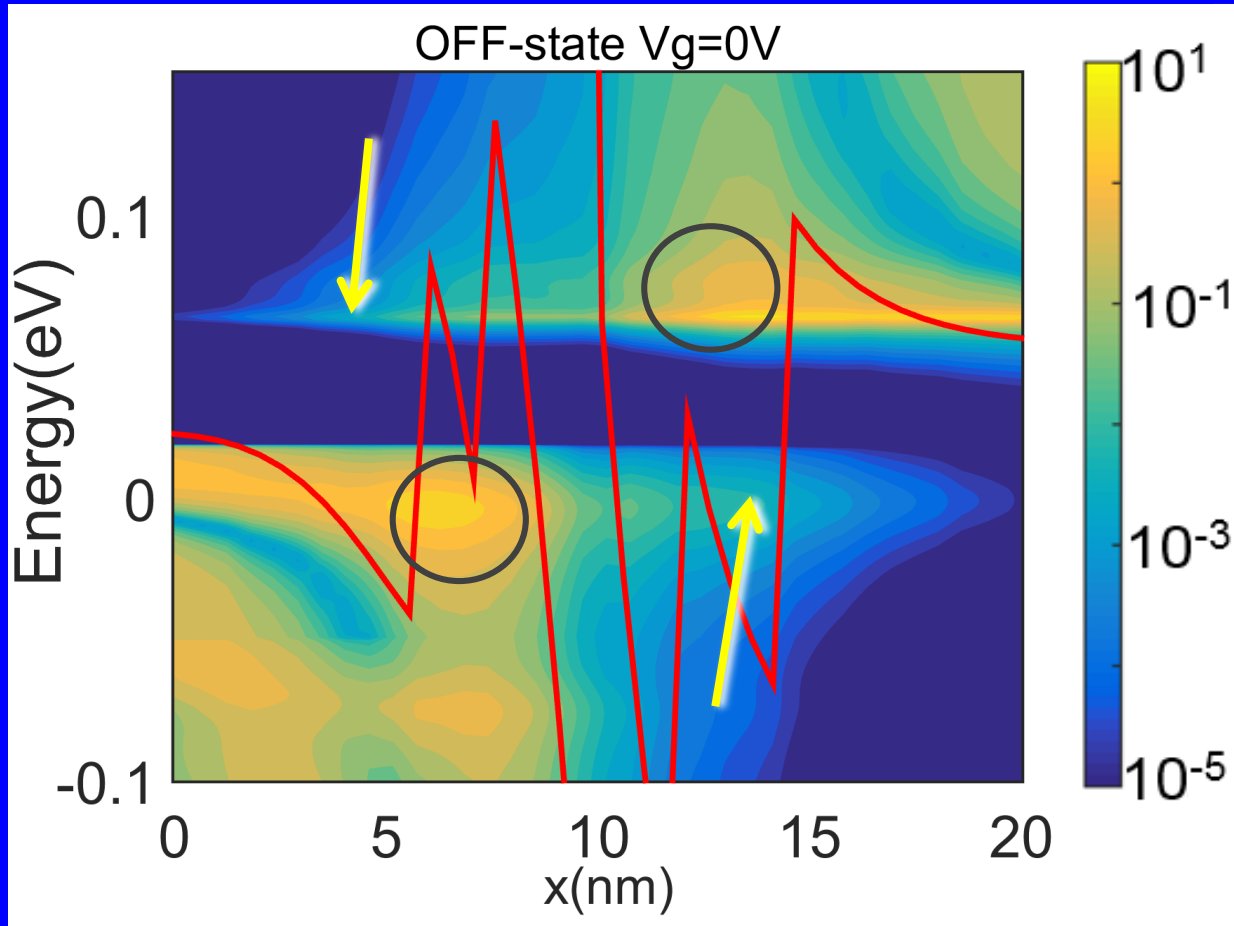
Role of the resonant bound states: ON-state

local density of states, $1/eV$



On-state: bound states increase transmission

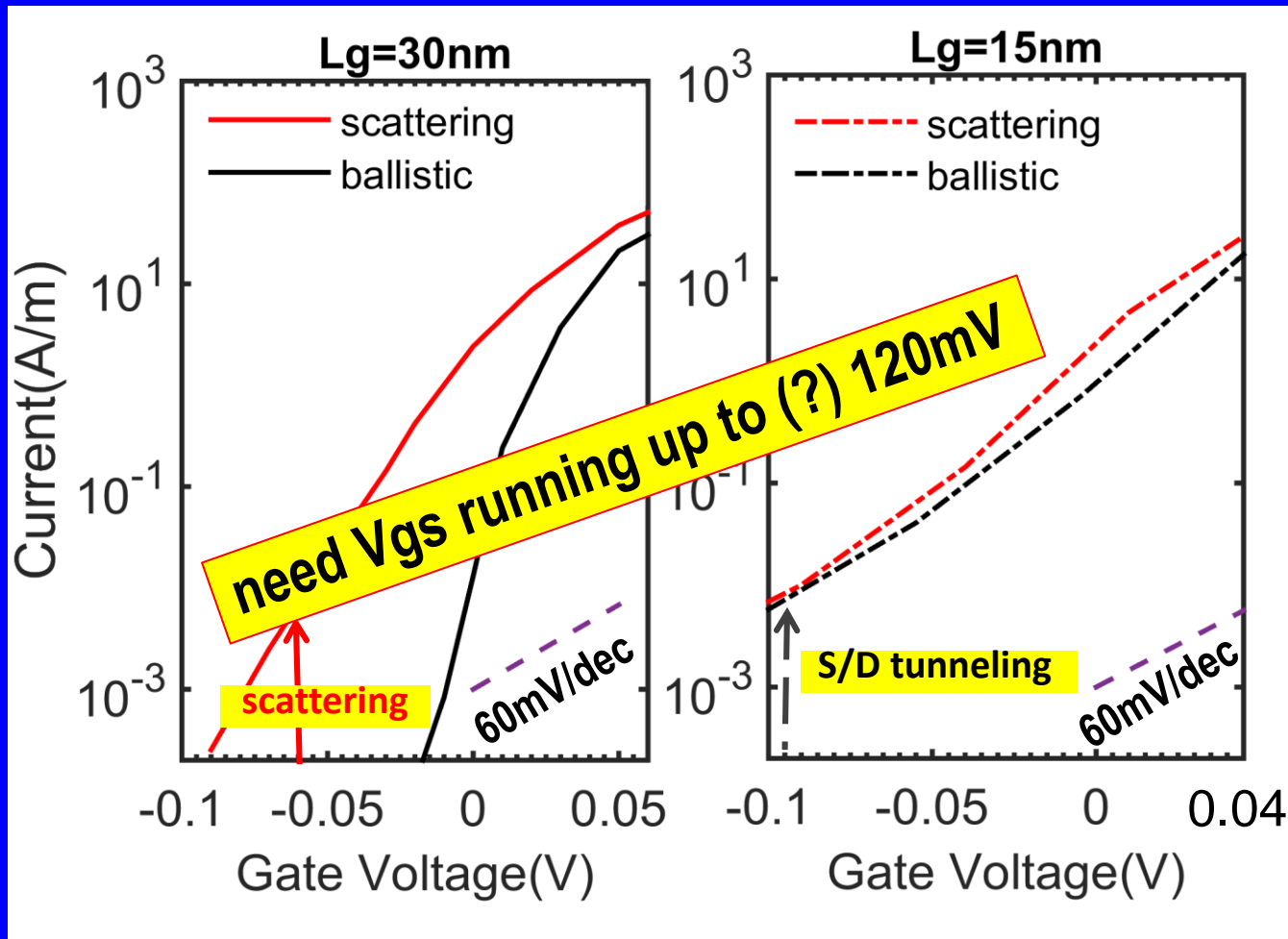
Role of the resonant bound states: OFF-state



- Phonon scattering:
 - *Off-state: evanescent tails of bound states \rightarrow leakage between two states \rightarrow Keep the bound state energies near the well edge energies*

$L_g=30\text{nm}$: I_{off} limited by scattering

$L_g=15\text{nm}$: I_{off} limited by S/D tunneling

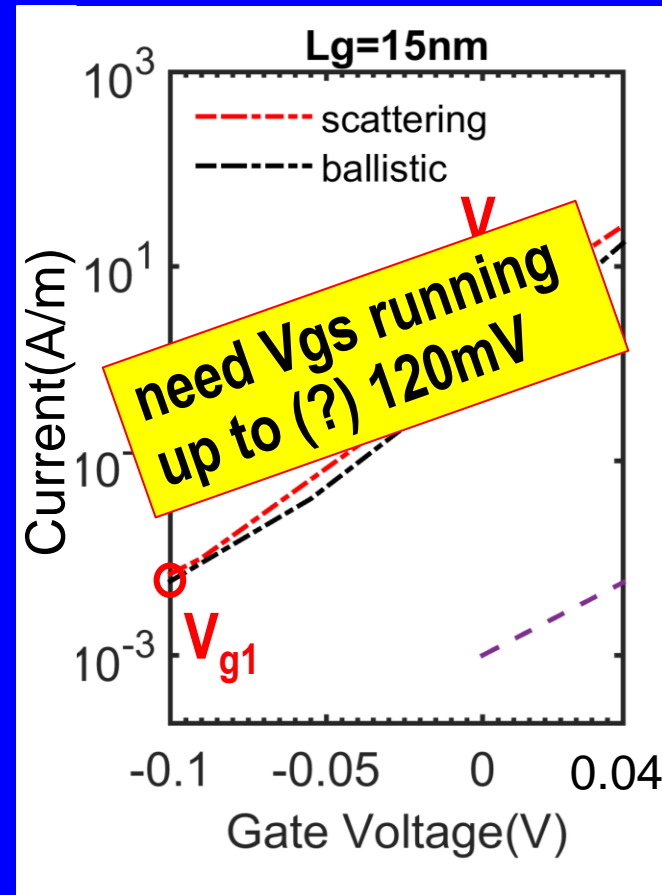
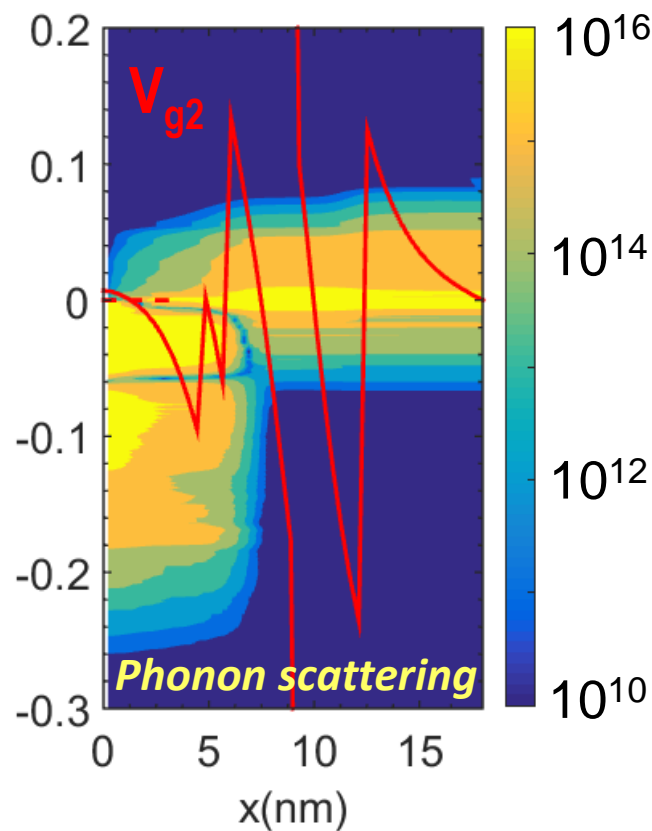
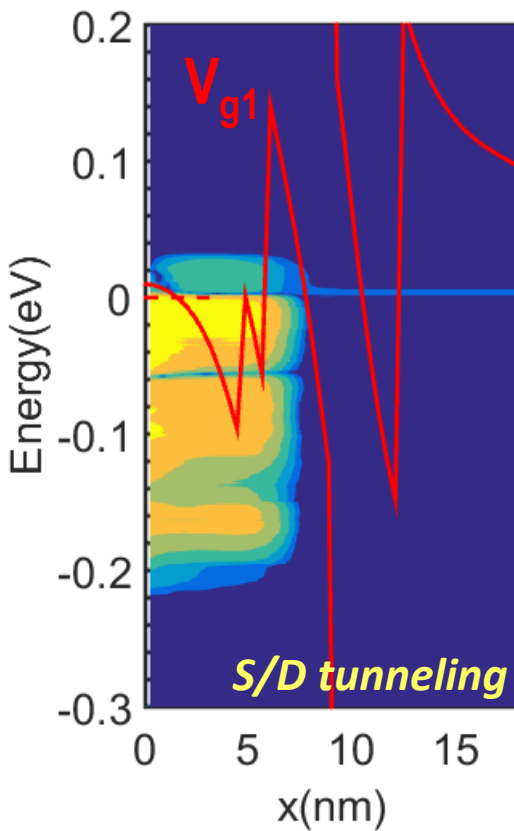


At 30nm L_g , V_{DD} must be increased $\sim 0.07\text{V}$ to maintain on/off ratio
At 15nm L_g , on/off ratio limited by S/D tunneling

Simulations use 220meV/nm optical deformation constant, consistent with $\mu=1.1 \times 10^5 \text{ cm}^2\text{V}^{-1}\text{s}^{-1}$.

Leakage at $L_g=15\text{nm}$

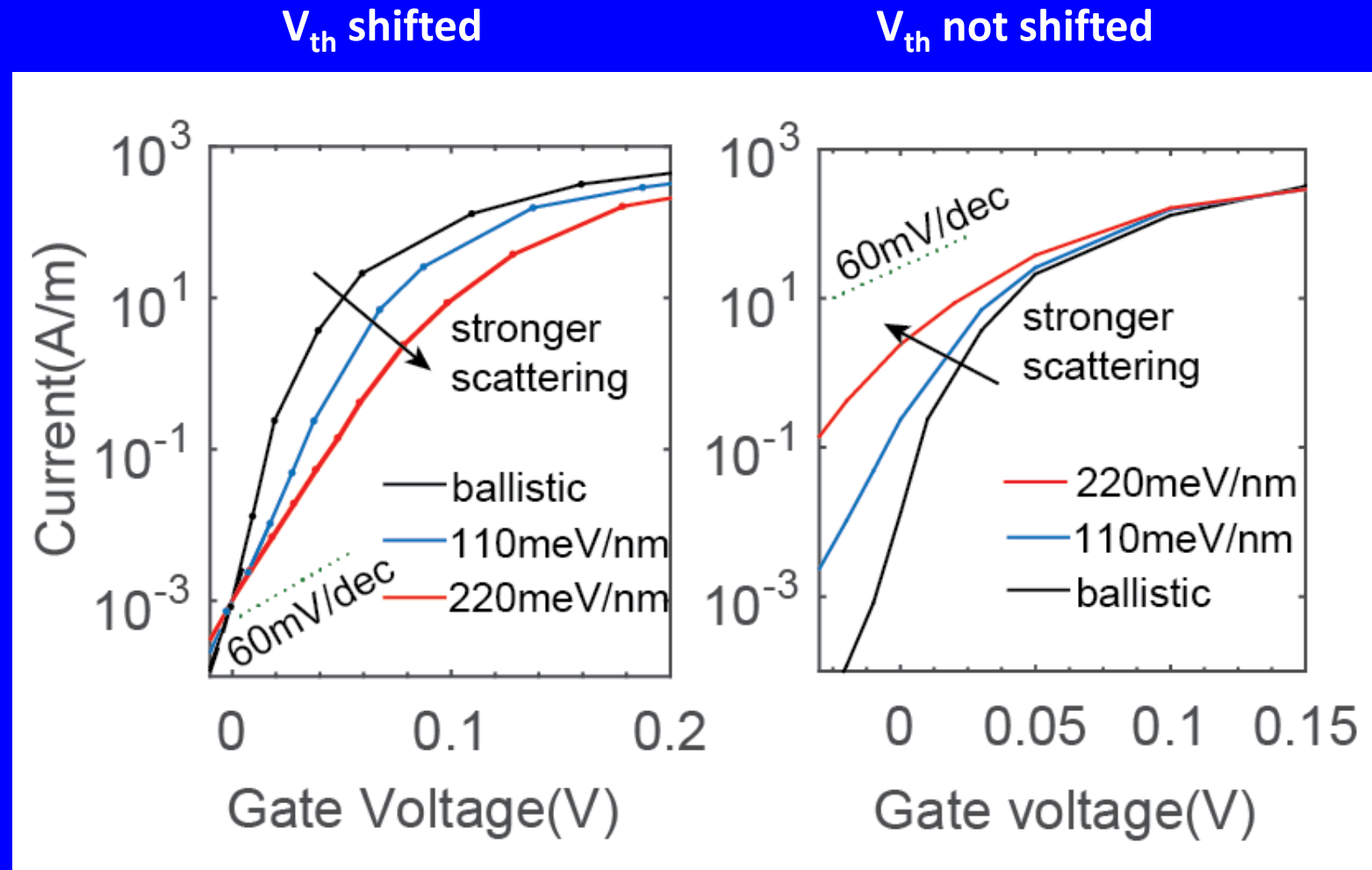
Local current density
(absolute value of current)



V_{g1} (close to off): current limited by *S/D tunneling*

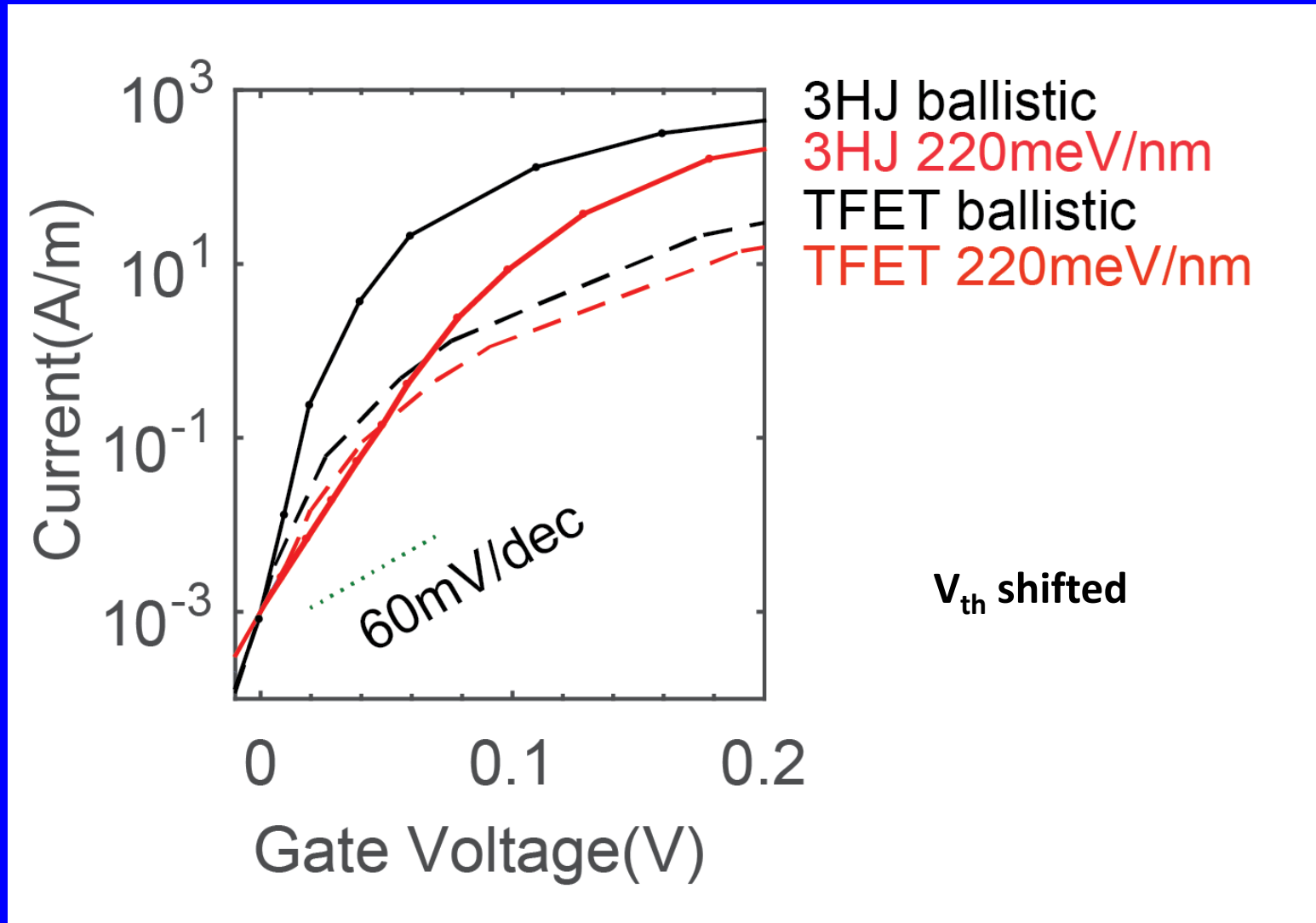
V_{g2} : current limited by *phonon scattering*

Phonon-Assisted Tunneling: 3HJ-TFET



S.S. and I_{off} increased with intensity of phonon scattering

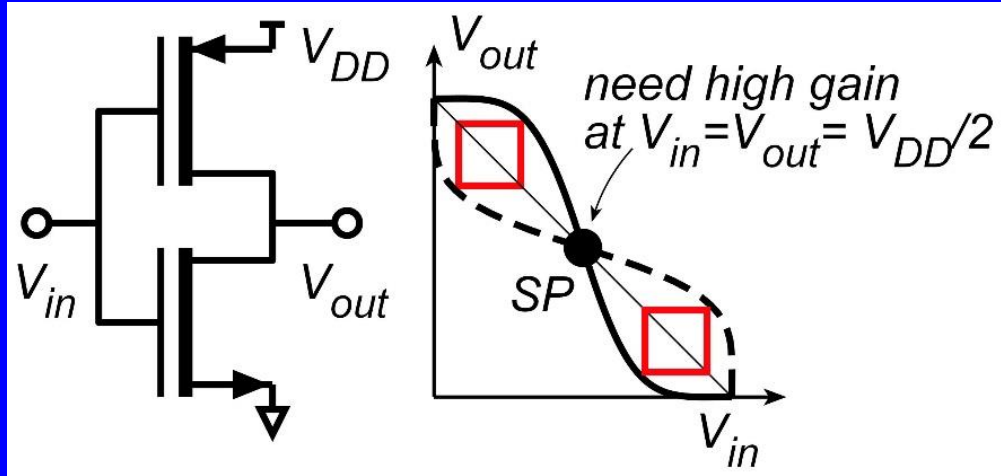
Phonon-Assisted Tunneling: TFET vs. 3HJ-TFET



Even with P.A.T., 3HJ design provides much larger I_{ON} than TFET

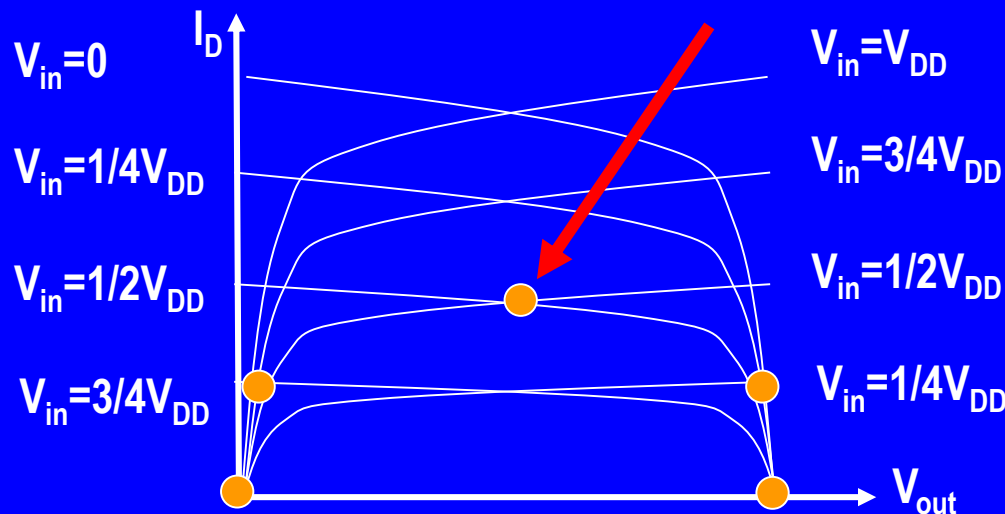
Noise margin sets a minimum threshold voltage

Need high voltage gain dV_{out}/dV_{in} at **switching point**



$$\text{Gain} = dV_{out}/dV_{in} = \frac{dI_D/dV_{GS}}{dI_D/dV_{DS}}$$

→ FET I_D - V_{DS} curve should be saturated (flat) at the **switching point**



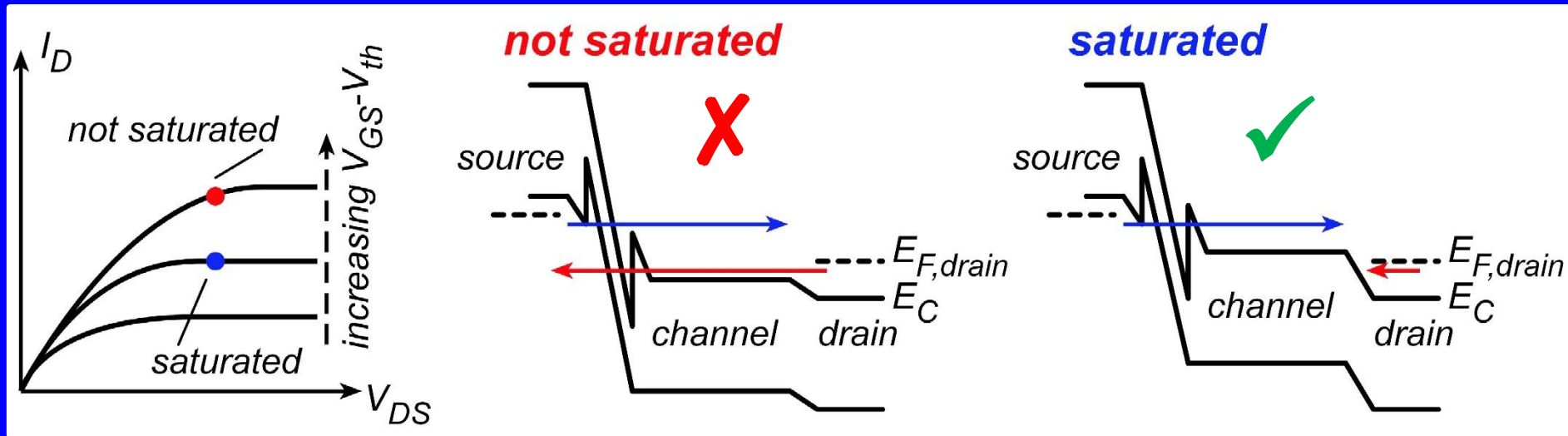
$E_{F,drain}$ should be below E_C at switching point

Need low output conductance when biased at switching point

output conductance: from drain-source reverse injection

to avoid : need drain Fermi level below channel conduction band

must decrease $(V_{GS}-V_{th}) \rightarrow$ increase V_{th}



Increasing the threshold voltage:
Improves the noise margin
Reduces I_{ON} . Also reduces I_{OFF}

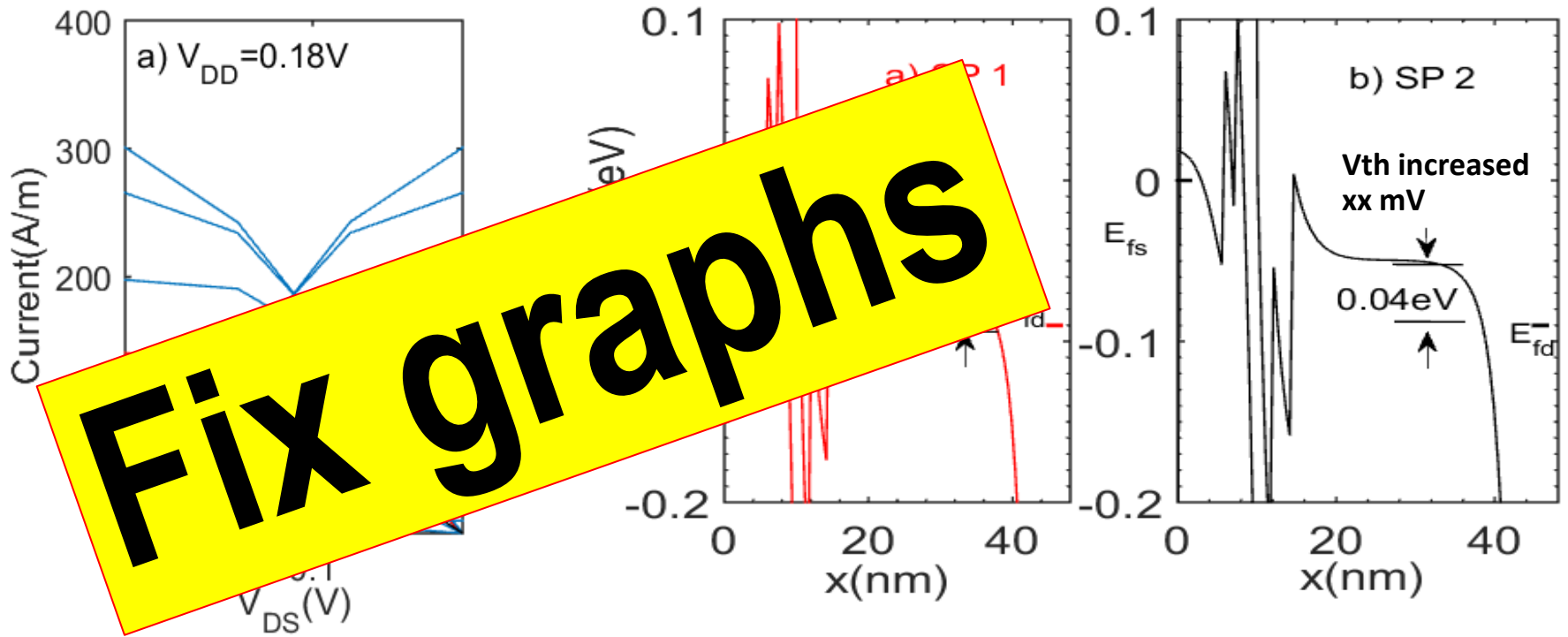
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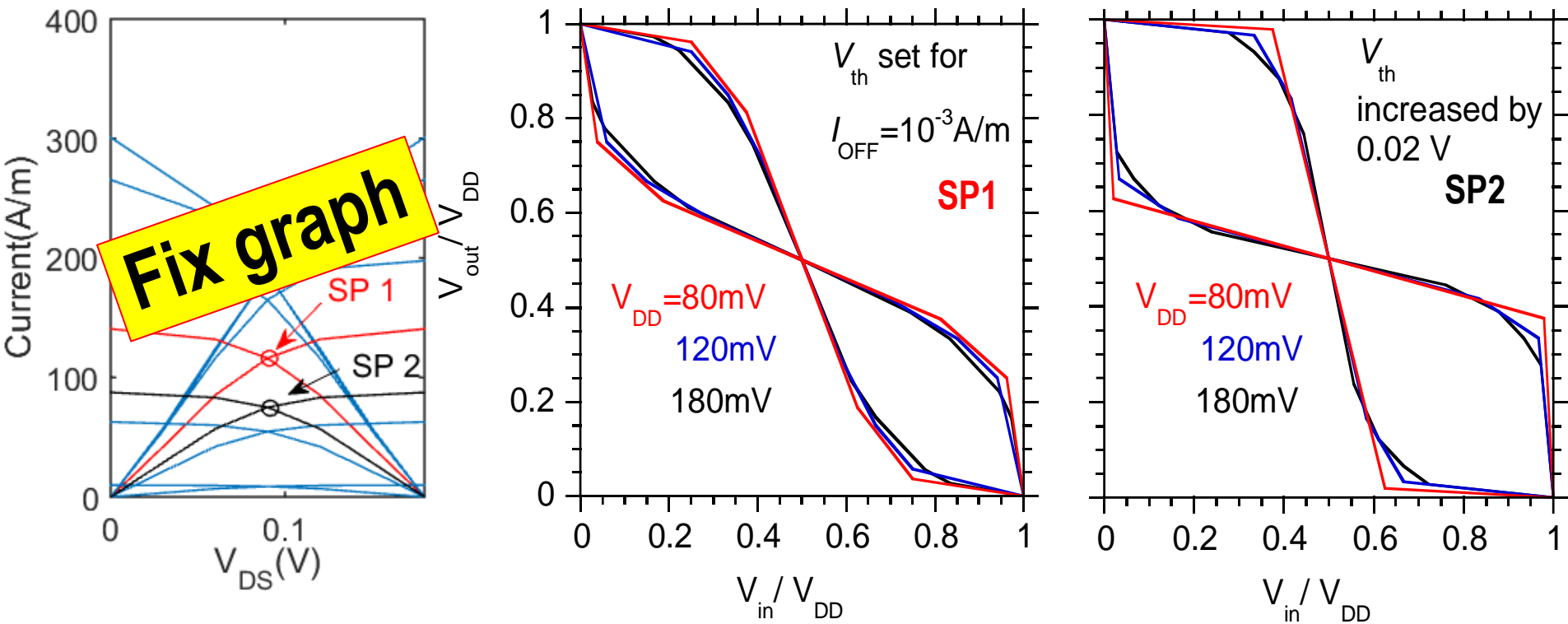


Increasing the threshold voltage:

Improves the noise margin

Reduces I_{ON} . Also reduces I_{OFF}

Increasing V_{th} increases noise margin



SP1:

FET not saturated \rightarrow large dI_D/dV_{DS} \rightarrow low gain, small noise margin

SP2:

V_{th} increased 20 mV \rightarrow FET *is* just saturated.

Small dI_D/dV_{DS} \rightarrow large gain, large noise margin

Increasing V_{th} decreases I_{on} from 106 A/m to 60 A/m at $V_{DD} = 0.08\text{V}$

Tunnel FET Design for High-Current, 120 mV Operation

Low energy computing
is low-voltage computing

MOSFETs:

60 mV/dec.

set minimum ~ 500 mV operation.

Tunnel FETs:

subthreshold swing

small on-current

~ 120 mV/dec.

\rightarrow extremely slow logic

Heterojunction FETs:

increased junction field, resonant states.

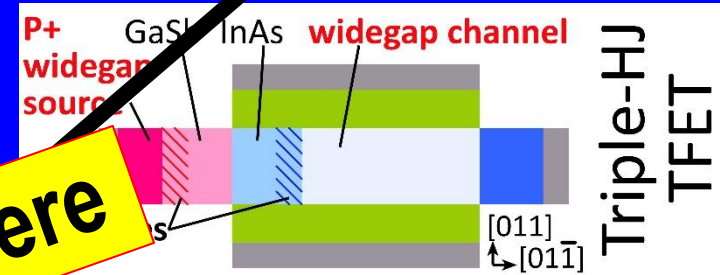
$>50\%$ tunneling probability; full energy range

N-TFET & PTFET designs.

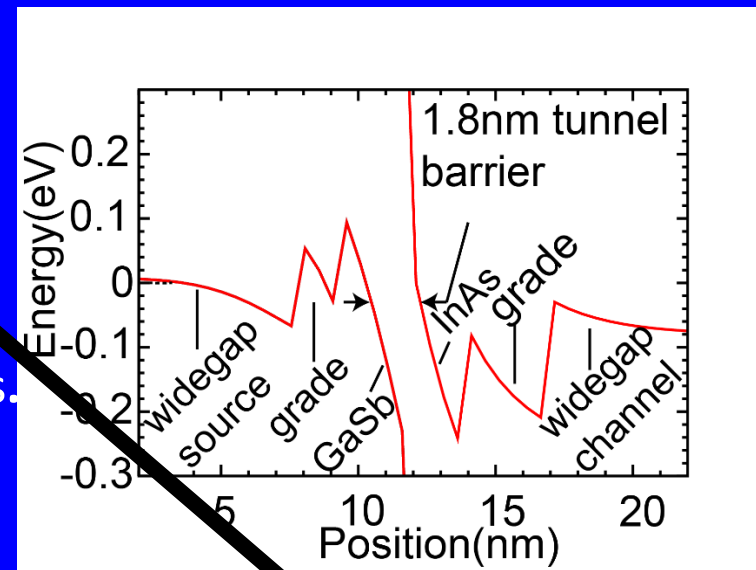
Designs using semiconductors with good high-K's.

Future work:

modeling leakage: scattering, defects.



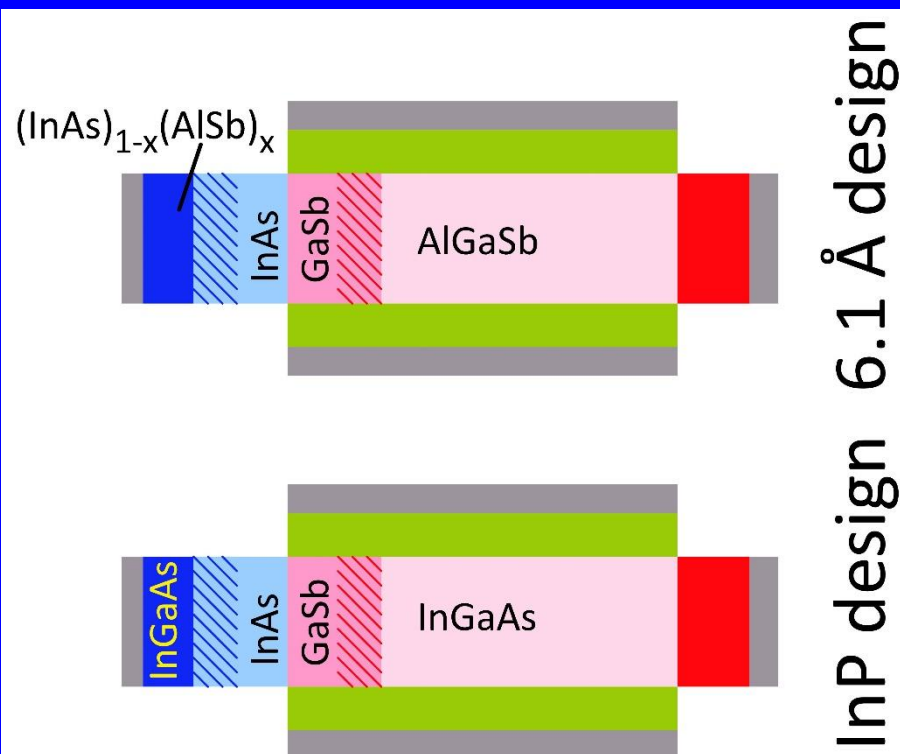
you have all the wrong words here



(end)

P-Channel designs

J. Huang *et al.*, in review (also arXiv preprint 1605.07166)



6.1 Å design:

No demonstrated high-quality dielectrics

InP-based design:

channel is InAs/InGaAs/InP
Some unpublished UCSB data suggesting good high-K interfaces on p-type InGaAs (Chobpattana, Stemmer) working to verify now

Simulations: (10^{-3} A/m I_{OFF} , 300 mV V_{DD})

6.1 Å design: 580 A/m I_{on}
comparable to N-TFET

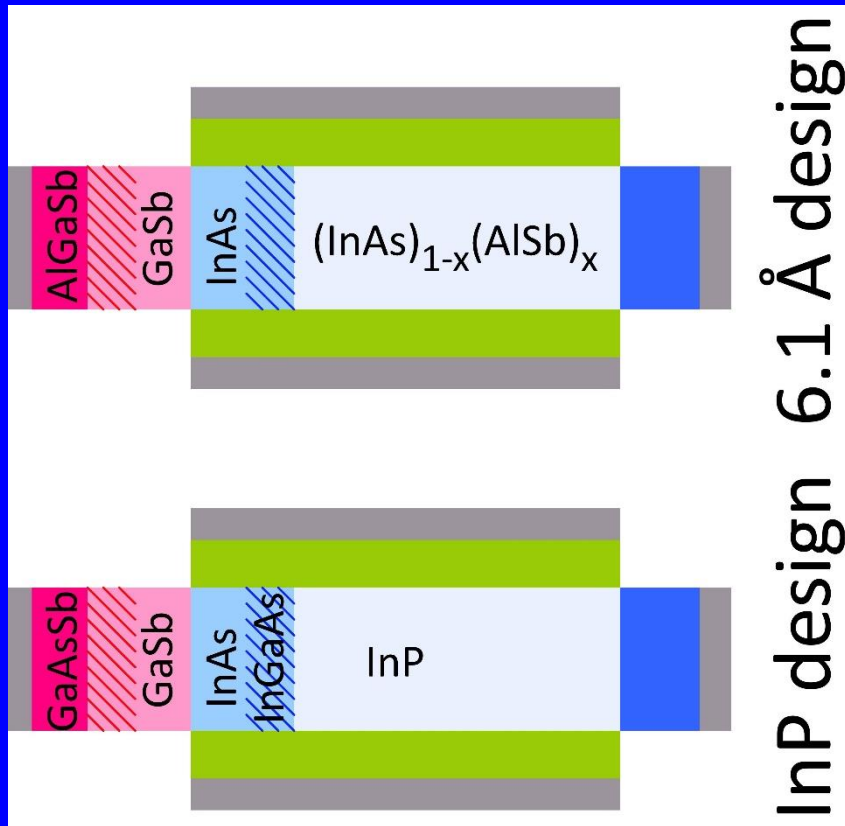
InP design: not yet simulated.

P-TFET performance is similar to that of the N-TFET

J.Z. Huang, et al, J-EDS, Vol 4, No.6, Nov 2016

Designs compatible with high-quality dielectrics

P. Long *et al.*, 2016 IEEE IPRM conference



6.1 Å design:

No demonstrated high-quality dielectrics

InP-based design:

channel is InAs/InGaAs/InP
high-quality dielectrics for all of these
Chobpattana, Stemmer, APL, 2014.

MOSFETs: 61 mV/dec. InAs,
65mV/dec. InGaAs
67mV/dec. InP

Simulations: (10^{-3} A/m I_{OFF} , 300 mV V_{DD})

InP design: 380 A/m I_{on}

6.1 Å design: 800 A/m I_{on} .
(need to improve design)

Triple-heterojunction design can be realized with high-quality dielectrics.

Present designs can be further improved.

Performance comparisons (ideal ballistic case)

$L_g=30\text{nm}$

Design	V_{DD}	relative switching energy $\propto V_{DD}^2$	$I_{on}@10^{-3} \text{ A/m } I_{off}$	speed F.O.M. I_{on}/V_{DD}
Si NMOS (experimental)	700 mV	1	~1000 A/m	~1400 S/m
Si NMOS (simulated)	700 mV	1	4080 A/m	5830 S/m
GaSb/InAs TFET	300 mV	0.18	32 A/m	107 S/m
GaSb/InAs TFET	70 mV	0.01	0.34 A/m	4.86 S/m
3HJ-TFET; 0.3V design	300 mV	0.18	800 A/m	2670 S/m
3HJ-TFET; 70mV design	70 mV	0.01	61 A/m	871 S/m

70 mV operation → 100:1 less switching energy than 700 mV CMOS

3HJ TFET @ 70 mV: 6.7:1 slower than CMOS

GaSb TFET @70 mV: 1200:1 slower than CMOS

Caveats:

Simulations ignore scattering: with it, what performance will we then obtain ?

Structure is complex: can we make it ?

Can we reduce threshold variations, or at least compensate for them ?